What is claimed is:

- An in-plane switching mode LCD device comprising: first and second substrates;
- 5 data and gate lines on the first substrate to define a plurality of pixel regions;
 - at least one data electrode on the first substrate;
 - at least one common electrode on the first substrate;
 - a transparent conductive film electrically connected with the common electrode; and
 - a liquid crystal layer between the first and second substrates.
 - The device of claim 1, wherein the transparent conductive film includes indium tin oxide (ITO).
 - The device of claim 1, further comprising a gate insulating film on the common electrode.
- 4. The device of claim 1, further comprising a passivation film on the common electrode.
- 5. The device of claim 4, wherein the common electrode is electrically connected with the transparent conductive film 25 through a contact hole in the passivation film.

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- 6. The device of claim 1, wherein the common electrode is electrically connected with the transparent conductive film through a laser welding.
- 7. The device of claim 1, wherein the liquid crystal layer

includes a cyano (CN) based liquid crystal.

- 8. The device of claim 1, wherein the liquid crystal layer includes a fluorine (F) based liquid crystal.
- The device of claim 1, wherein the transparent conductive film is formed outermost to the common electrode.
- 10. The device of claim 1, wherein the transparent conductive film extends toward the data electrode.
- 11. A method for manufacturing an in-plane switching mode LCD device comprising:
- 20 providing first and second substrates;
 - forming a plurality of gate lines and common electrodes on the first substrate;
 - forming a gate insulating film on the common electrodes;
- forming a plurality of data lines and data electrodes on 25 the gate insulating film;

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forming a transparent conductive film electrically connected with the common electrodes; and

forming a liquid crystal layer between the first and second substrates.

- 12. The method of claim 11, wherein the common electrode is selected from the group of consisting of Al, Cr, Ti and Al alloy.
- 13. The method of claim 11, further comprising the step of forming a passivation film on the data electrodes.
- 14. The method of claim 11, wherein the common electrode is electrically connected with the transparent conductive film through a contact hole of the passivation film.
- 15. The method of claim 11, further comprising the step of electrically connecting the common electrodes with the transparent conductive film.
- 20 16. The method of claim 15, wherein the common electrode is electrically connected with the transparent conductive film through a laser welding.
- 17. The method of claim 11, wherein the transparent conductive film includes indium tin oxide (ITO).

- 18. The method of claim 11, wherein the liquid crystal layer includes a cyano (CN) based liquid crystal.
- 5 19. The method of claim 11, wherein the liquid crystal layer includes a fluorine (F) based liquid crystal.
 - 20. The method of claim 11, wherein the transparent conductive film is formed outmost to the common electrodes.
 - 21. The method of claim 11, wherein the transparent conductive film extends toward at least one of the data electrodes.